

ABSTRACT OF THE DISCLOSURE

Disclosed is an exposure method in which high precision focus calibration is realized by measuring a tilt of an image plane in a scanning direction, so 5 that exposure with a high resolution can be performed.

The exposure method includes: a measuring step of measuring a position of an image plane of a projection optical system at a plurality of measurement positions different from each other with 10 respect to a scanning direction; and a correcting step of correcting a tilt of the image plane of the projection optical system based on measurements.